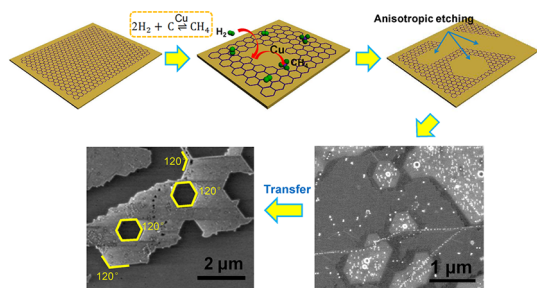


## Correction to Anisotropic Hydrogen Etching of Chemical Vapor Deposited Graphene

**Graphene** [ACS Nano 2012, 6, 126–132. DOI: 10.1021/nn202996r]. Yi Zhang, Zhen Li, Pyojae Kim, Luyao Zhang, and Chongwu Zhou\*

The bottom two SEM images in the original Table of Contents graphic were misplaced for etched graphene before and after transfer. We swapped the two SEM images and the corrected Table of Contents graphic is shown below.



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